

TSMC-02-1033



January 13, 2004

To: Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/696,006 10/29/03 |

Kuo-Chi Tu

STRUCTURE FOR REDUCING LEAKAGE
CURRENTS AND HIGH CONTACT RESISTANCE
FOR EMBEDDED MEMORY AND METHOD FOR
MAKING SAME

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.


The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on January 27, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

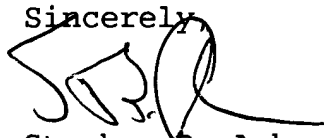
 1/27/04

TSMC-02-1033

U.S. Patent 6,403,417 to Chien et al., "Method for In-situ Fabrication of a Landing Via and a Strip Contact in an Embedded Memory," describes a method for making via holes and strip contact holes for embedded memory.

U.S. Patent 6,485,988 to Ma et al., "Hydrogen-free Contact Etch for Ferroelectric Capacitor Formation," describes a method for using a hydrogen-free contact etch for ferroelectric capacitor formation.

Sincerely,

A handwritten signature in black ink, appearing to read 'SBA', with a long horizontal flourish extending to the right.

Stephen B. Ackerman,
Reg. No. 37761

Form PTO-1449

Document Number (Optional)

Application Number

TSMC-02-1033

10/696,006

Applicant

Kuo-Chi Tu

Filing Date

10/29/03

Group Art Unit

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILED DATE IF APPROPRIATE
	6403417	6/11/02	Chien et al.	438	241	3/13/01
	6485988	11/26/02	Ma et al.	438	3	12/19/00

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Portion of Pages, Etc.)

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.